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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Fumi NABESHIMA et al.	Atty. Docket No.: PA214WP002
Serial No.: 10/598,933	Confirmation No.: 2213
Filing Date: September 14, 2006	Group Art Unit: 1751
Title: Semiconductor wafer inspection device and method	Examiner: n/a

Date: August 15, 2007

Honorable Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450  
Mail Stop: Missing Parts

**REPLY TO NOTICE TO FILE MISSING PARTS OF NONPROVISIONAL  
APPLICATION**

Sir:

This communication is in reply to the NOTICE TO FILE MISSING PARTS OF NONPROVISIONAL APPLICATION ("the Notice") having a mailing date of **June 22, 2007**, a copy of which is enclosed herewith.

Specifically, it is asserted that the statutory basic filing fee of \$300, the application search fee of \$500, and the application examination fee of \$200 – a total of \$1,000 – have not been paid in this application. In addition, it is asserted that a surcharge of \$130 for late submission of such fees as set forth in 37 CFR 1.16(f) must also be submitted.

The Applicant originally intended the present application as a filing under 35 U.S.C 371, and toward that end paid the statutory basic filing fee of \$300, the application search fee of \$400, and the application examination fee of \$200 – a total of \$900. Proof of payment of these fees can be seen in the enclosed MONTHLY STATEMENT OF DEPOSIT ACCOUNT for Deposit Account No. 50-3546 dated 9-26-06, specifically the three entries posted 9-15-06. It can be seen

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